OIPE JC109 MAY 24 2004 PATENT & TRADEMARK OFFICE

TFW

PATENT
Atty. Dkt. AMAT/4714.C1/TCG/WCVD/PJS

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Xi, et al.

Serial No.: 10/762,764

Filed: January 22, 2004

Confirmation No.: Unknown

For: Method and Apparatus for Depositing Refractory Metal Layers Employing Sequential Deposition Techniques to Form a Nucleation Layer

§

Group Art Unit: Unknown

Examiner: Unknown

MAIL STOP AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

CERTIFICATE OF MAILING
37 CFR 1.8
I hereby certify that this correspondence is being deposited on 5/21, 2004 with the United States Postal Service as First Class Mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

5/21/04 (Date) Kevin Zuhr (Signature)

Dear Sir:

PRELIMINARY AMENDMENT

Prior to examination, please amend the above-identified application as follows. **Amendments to the Specification** are shown beginning on page 2 of this paper. **The Pending Claims** are shown beginning on page 3 of this paper. **Remarks** begin on page 5 of this paper.